

Deposition Control and Depth Profiling in TaO_x Memristors

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What are Memristors

Resistive Memory

- Flash has reached its limit
 - What's next?

Panasonic
ideas for life

hp
in vent

ELPIDA

SanDisk

SAMSUNG

tsmc

TOSHIBA
Leading Innovation >>>

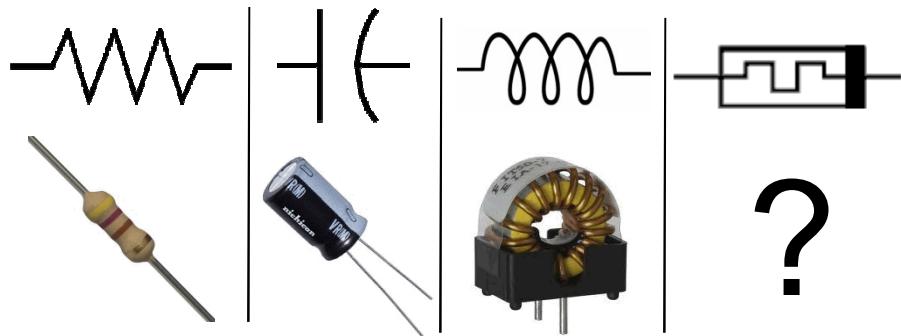
imec

hynix

micron

Novel Circuit Element

- Leon Chua in the 70's
 - Resistor, Capacitor, Inductor, ?



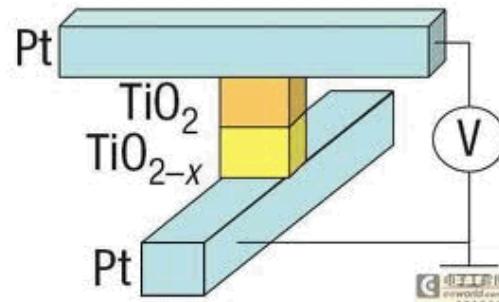
What are Memristors

Resistive Memory

- Performance in TaOx?
 - 30 nm (and shrinking)
 - Sub nanosecond switching
 - >10 year retention
 - ~10 pJ switching energy
 - CMOS compatible
 - Multi-level cell
 - 3D stackable
 - Simple architecture
- Remaining Issues?
 - Continued Scaling and Integration
 - Process Uniformity/Reproducibility
 - Forming Process
 - Nonlinearity

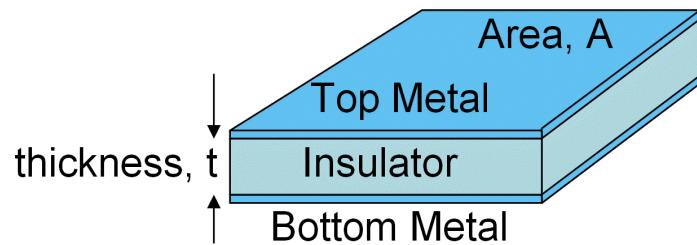
Novel Circuit Element

- HP in 2008 Showed One
 - Nanoscale TiO₂ is a memristor

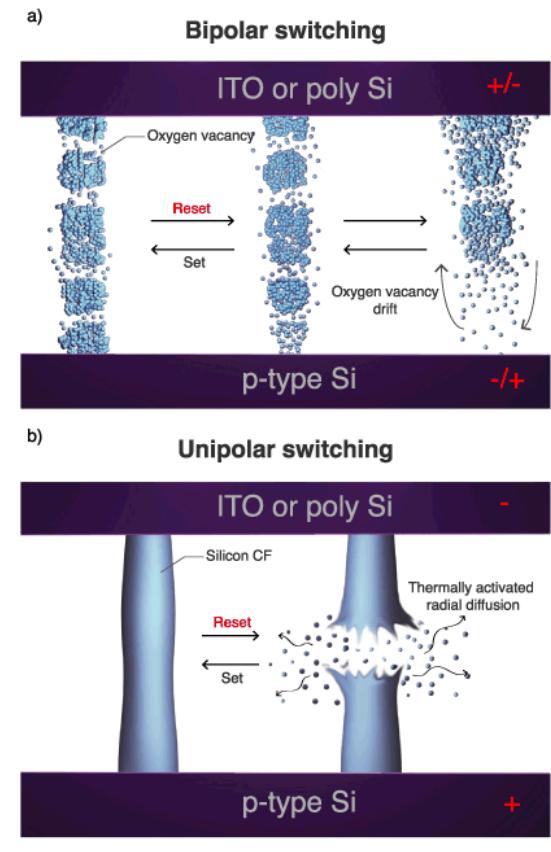
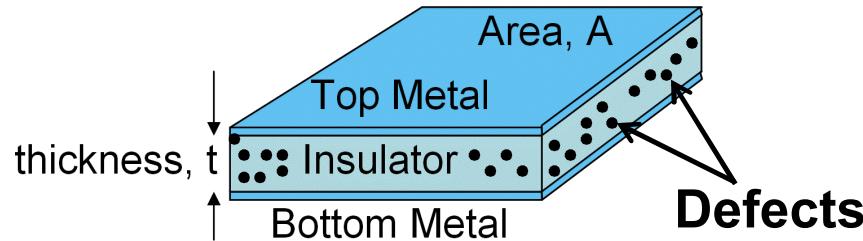


What are Memristors Really?

- A tantalum oxide metal-oxide-metal sandwich

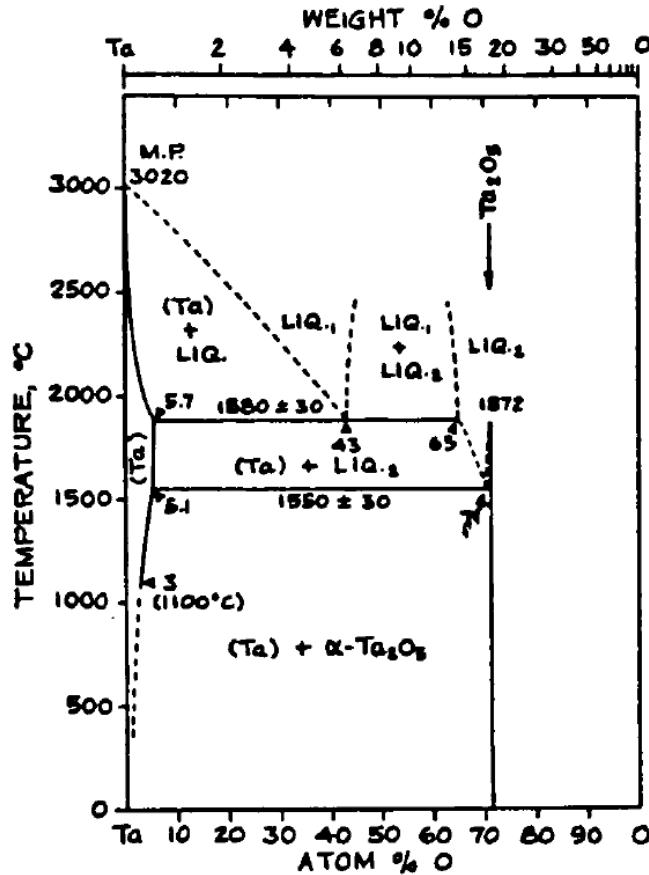


- Good oxides are bad memristors

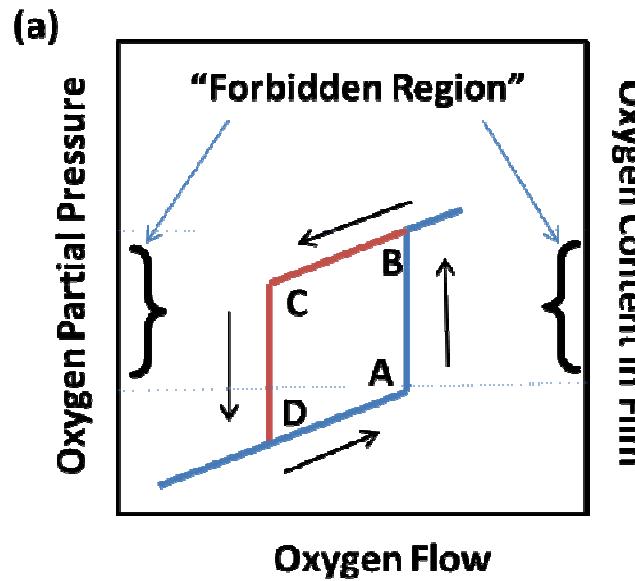


Making Bad Oxides is Hard

- Making bad oxides is harder than it sounds
- Tantalum Oxide wants to be either Ta or Ta_2O_5

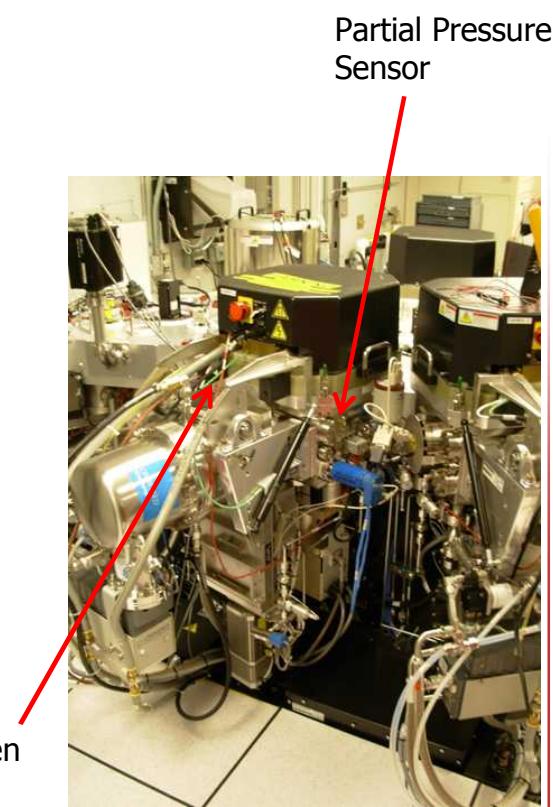
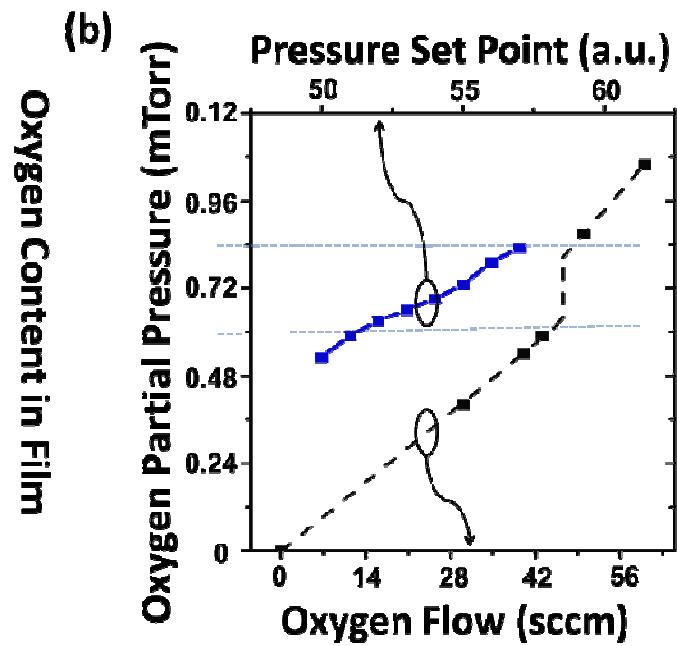
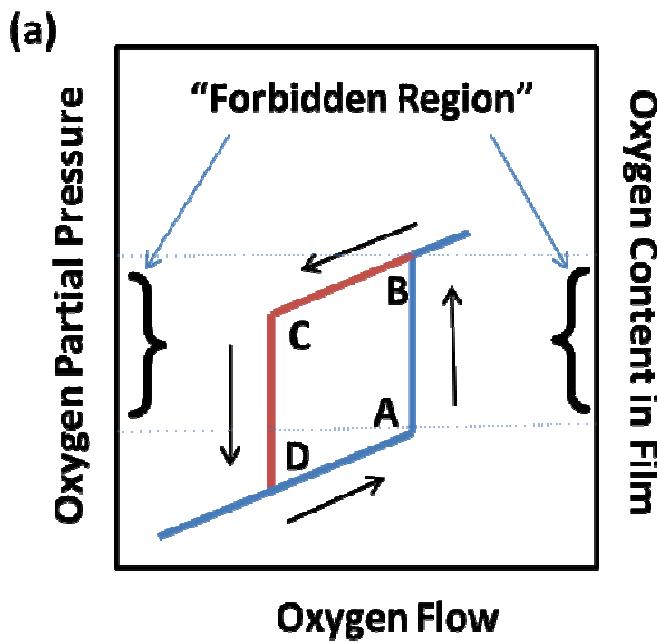


- Sputtering wants to deposit Ta or Ta_2O_5



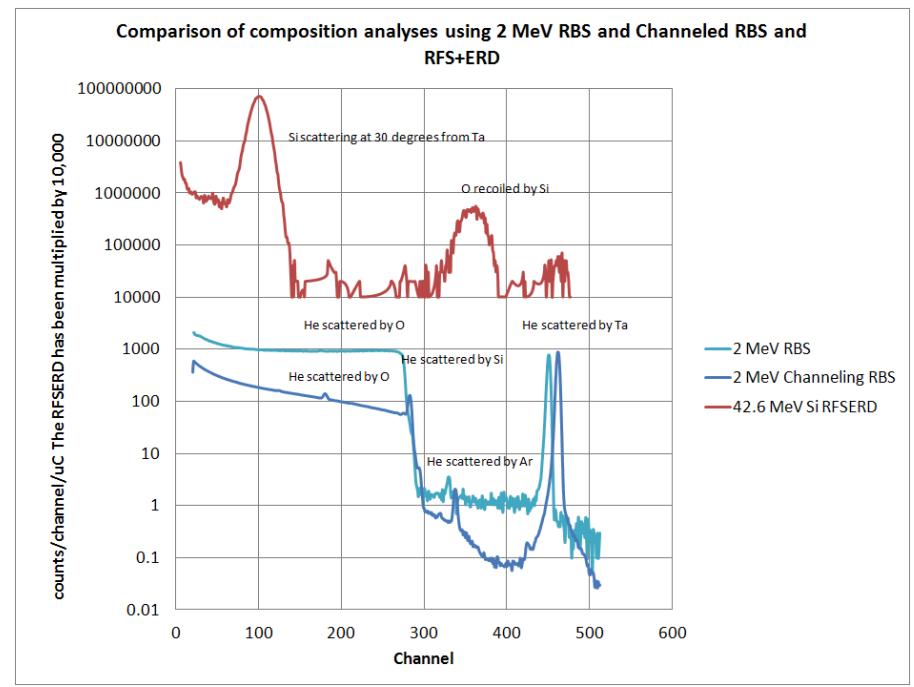
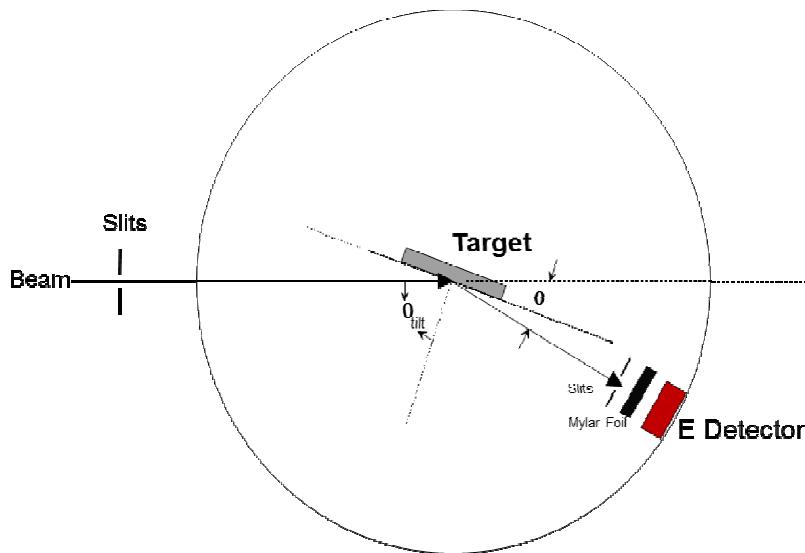
Making Bad Oxides is Hard

- But it can be done



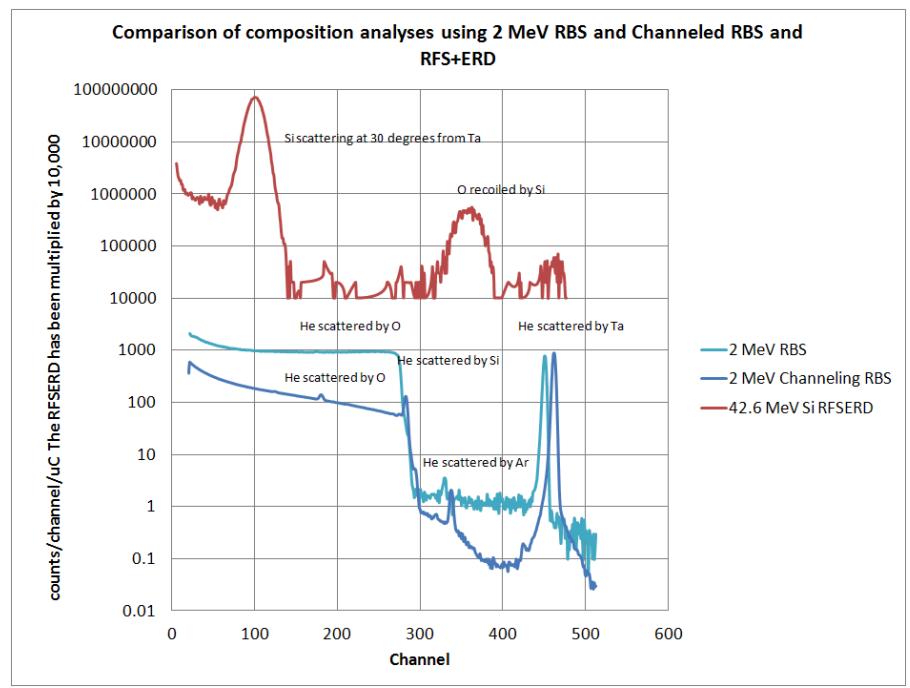
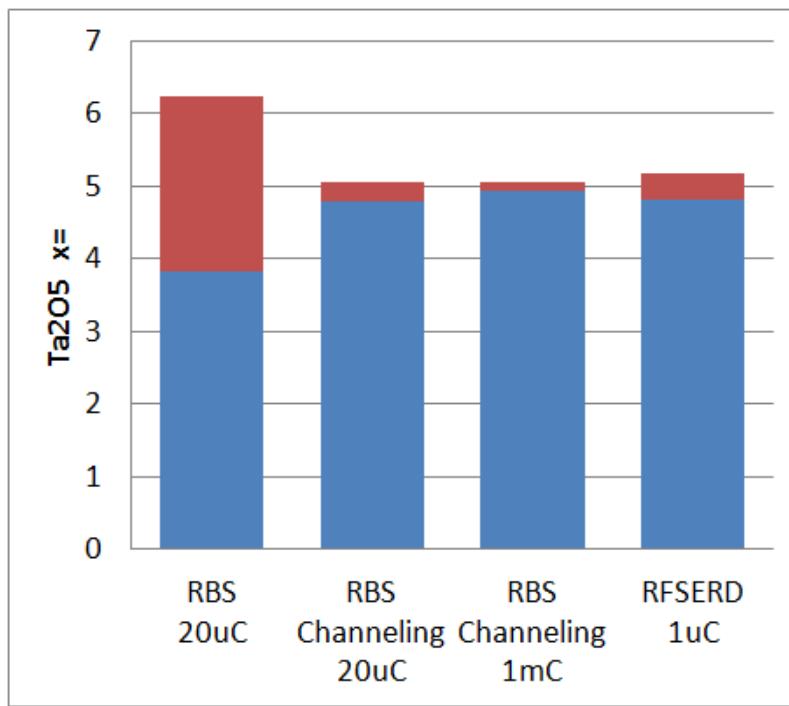
Calibrating Stoichiometry

- Measuring stoichiometry is challenging too
- Rutherford backscattering won't work!
- Developed a new characterization technique called RFSERD (Rutherford Forward Scattering and Elastic Recoil Detection).



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HAXPES

- Measure stoichiometry at varying depths
- Gives chemical bonding state as well as stoichiometry

$$\lambda = E/\{E_p^2[\beta \ln(\gamma E) - (C/E) + (D/E^2)]\}$$

$$\beta = -0.0216 + 0.944/(E_p^2 + E_g^2)^{1/2}$$

$$+ 7.39 \times 10^{-4} \rho$$

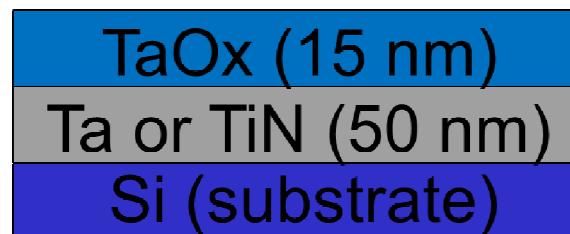
$$\gamma = 0.191 \rho^{-0.50}$$

$$C = 1.97 - 0.91U$$

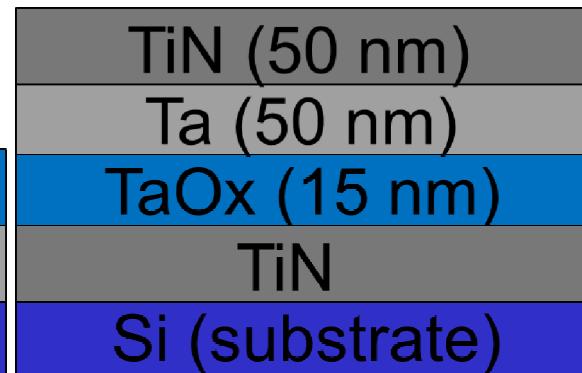
$$D = 53.4 - 20.8U$$

$$U = N_v \rho/M$$

HAXPES Stack



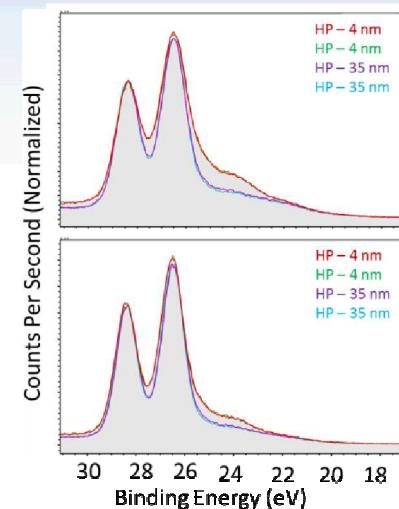
Typical Device Stack





HAXPES

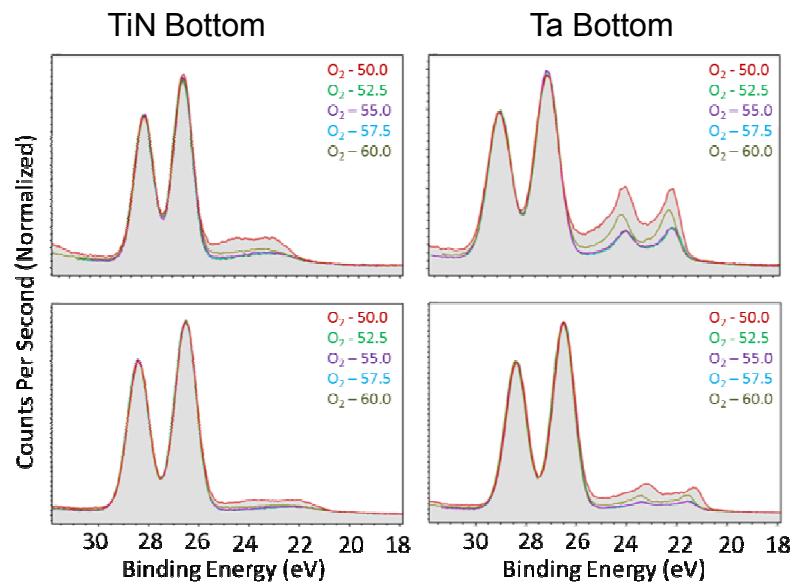
Collaborator Films



- Films made at Sandia are qualitatively different
- Depth and electrode dependence



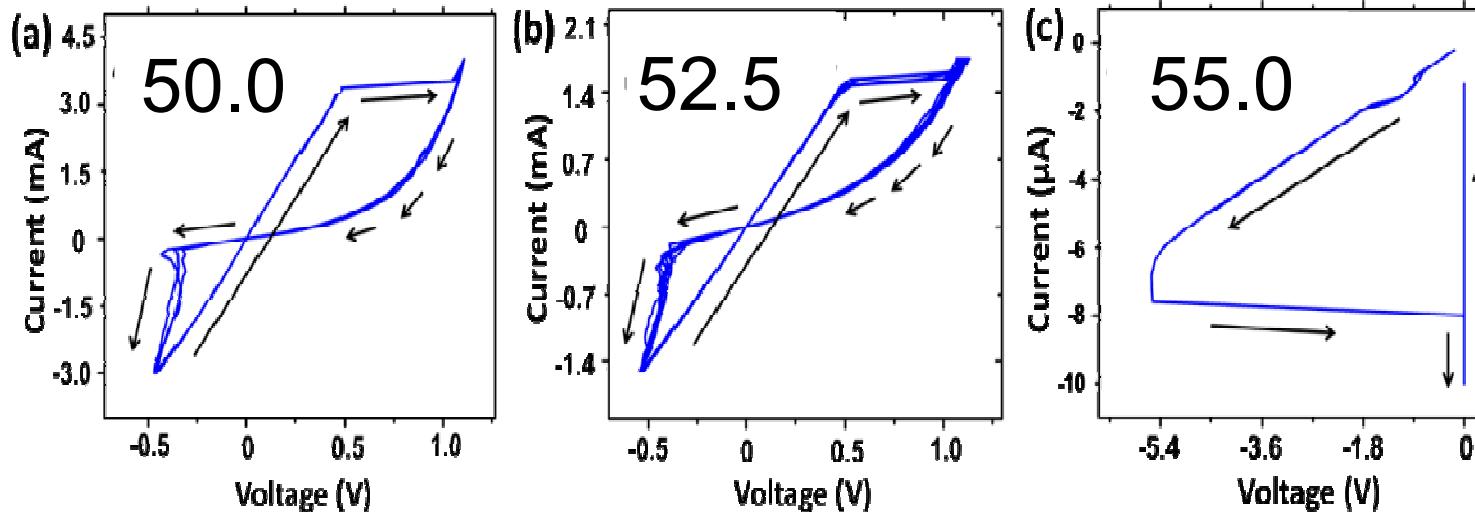
Sandia Films



Sandia-Made Devices

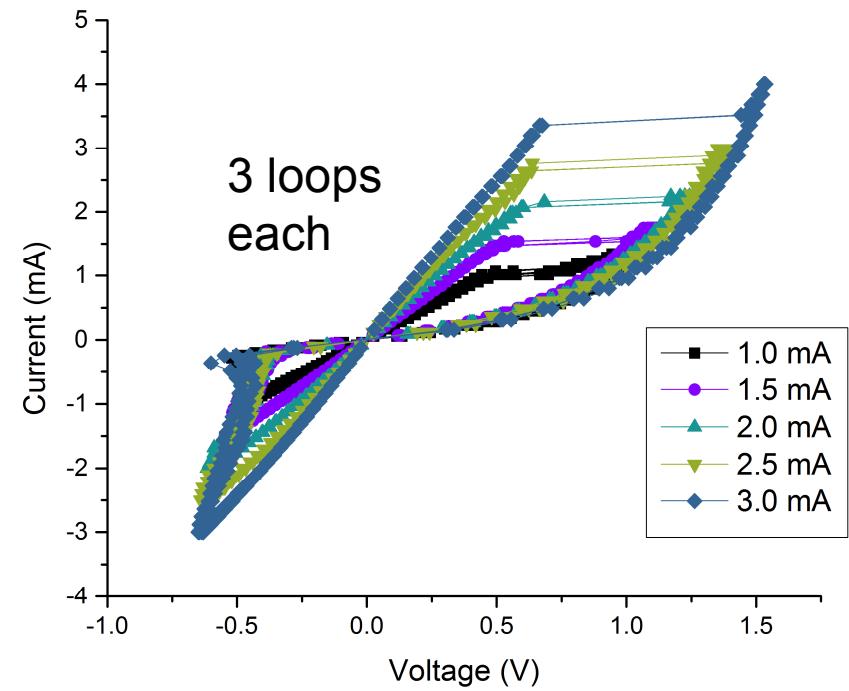
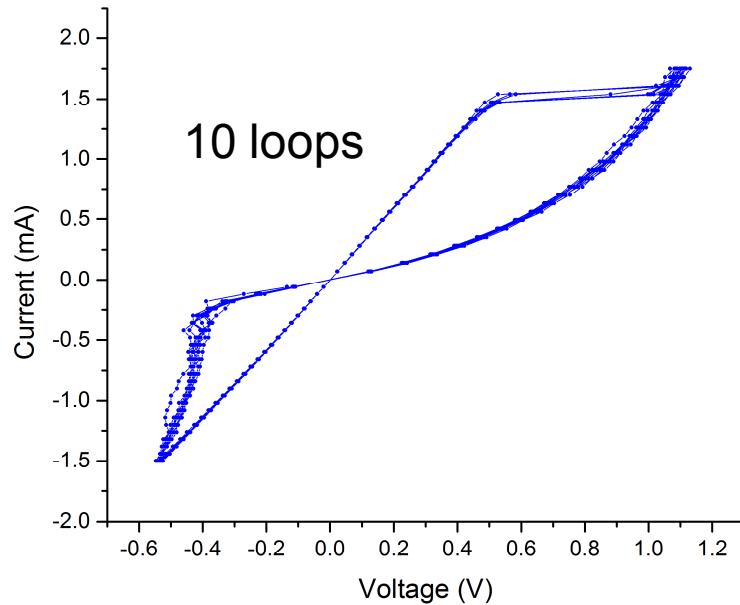
- Low oxygen flows gave forming free, low yield
- High oxygen flows gave devices that shorted easily
- Middle results best
 - Forming free
 - High yield

Partial Pressure Set	x: Ta ₂ O _x	Working Devices?
50.0	1.9 ± 0.5	Some
52.5	3.3 ± 0.5	Yes
55.0	4.2 ± 0.5	No
57.5	4.6 ± 0.5	No
60.0	5.0 ± 0.5	No



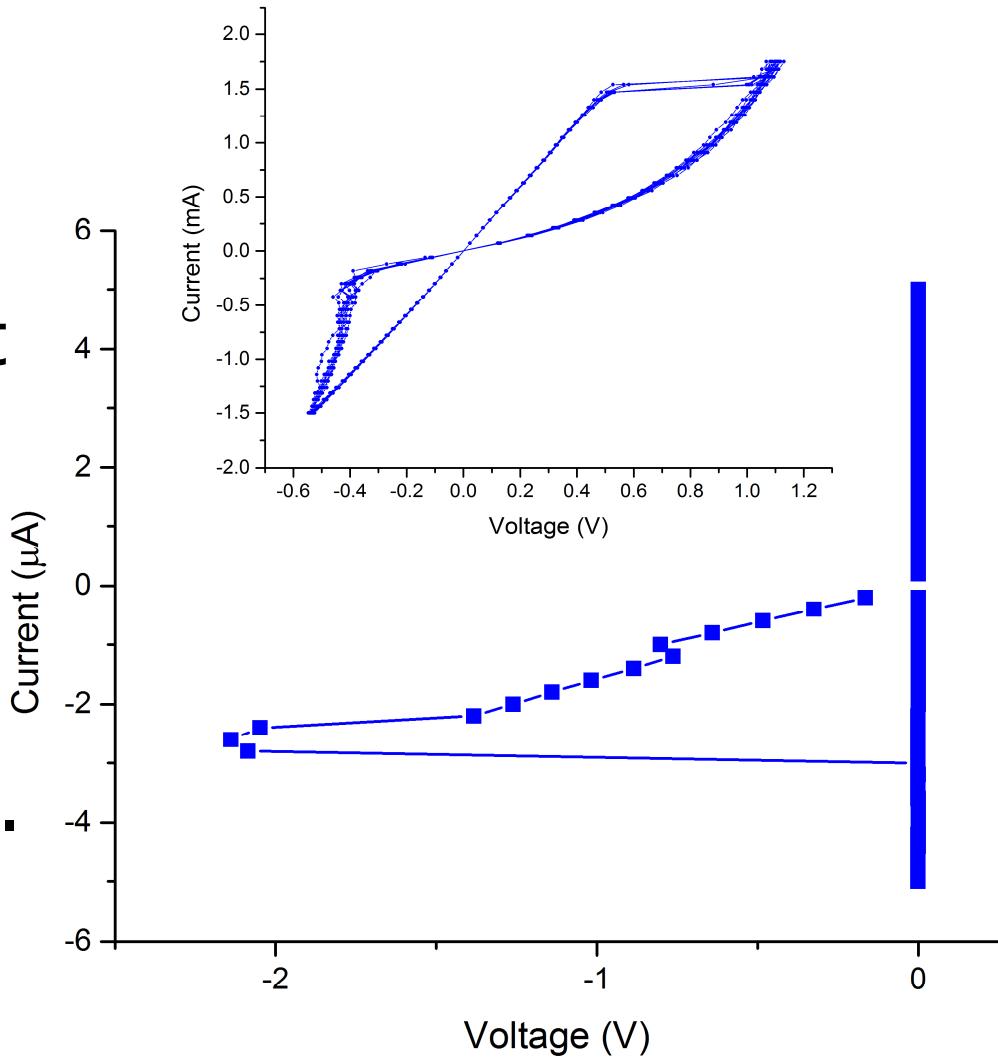
Sandia-Made Devices

- Low oxygen flows gave forming free, low yield
- High oxygen flows gave devices that shorted easily
- Middle results best
 - Forming free
 - High yield



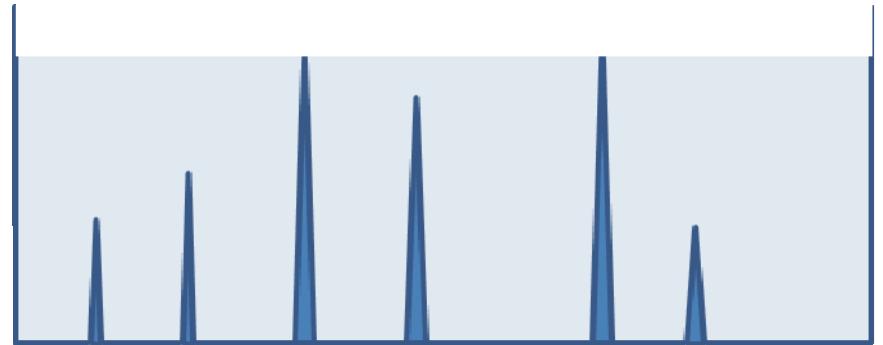
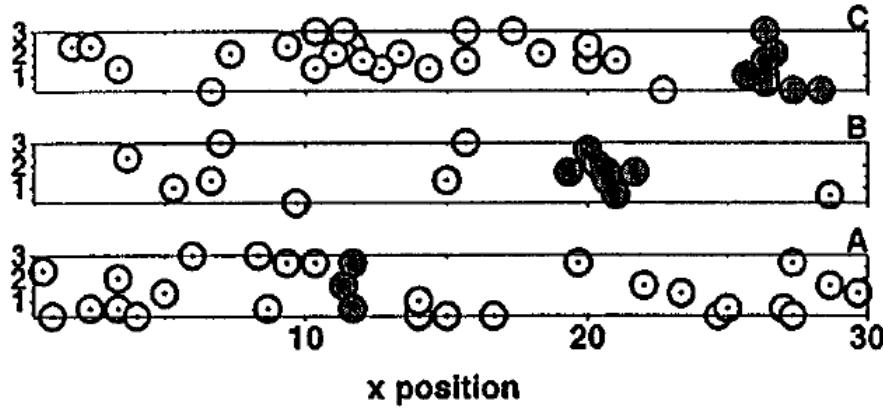
Annealing?

- Strange Reverse Forming Required
- Most likely the effect is some sort of anneal
- Possibly the filament is extended with negative feedback.



Possible Structure/Mechanism

- Possibly the OFF current anneals the device with negative feedback.
- Hard breakdown of thick oxides vs soft for thin



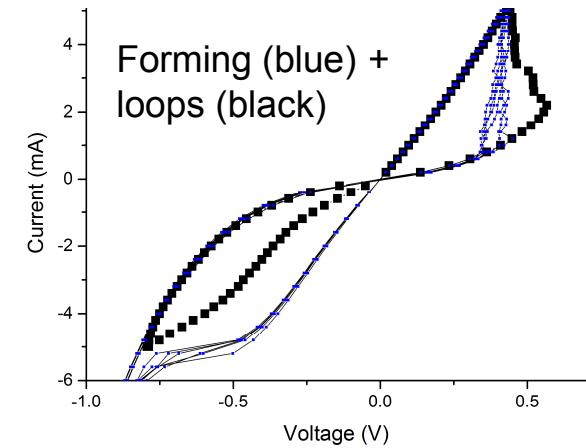
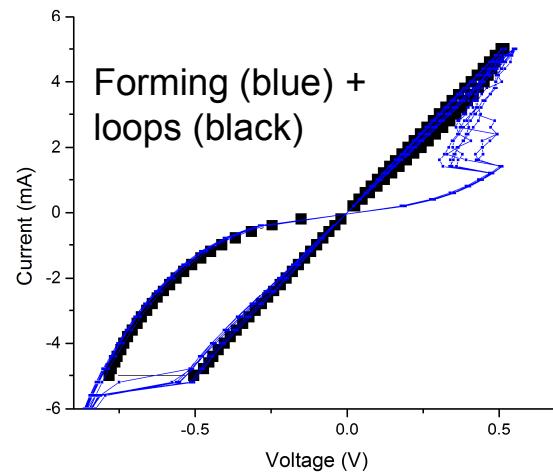
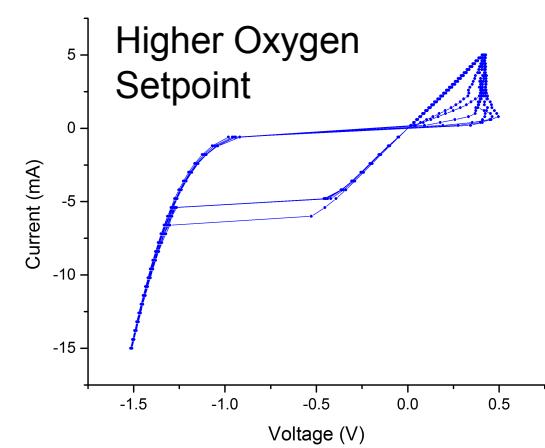
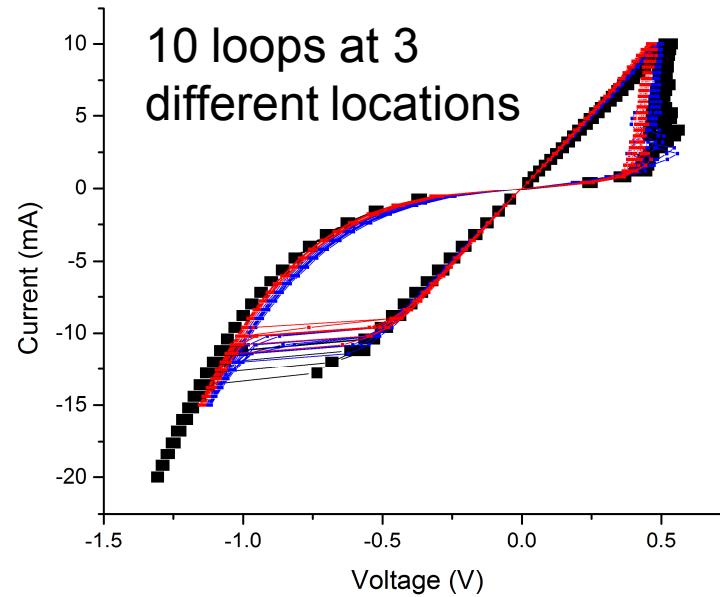


Summary

- We have developed a forming free memristor process
 - Process gives increased reproducibility
 - Papers to come soon
- We developed a new ion beam technique to characterize the films
- We learned about the chemical bonding and gradients in the films
- We are gaining insight into the forming and switching process

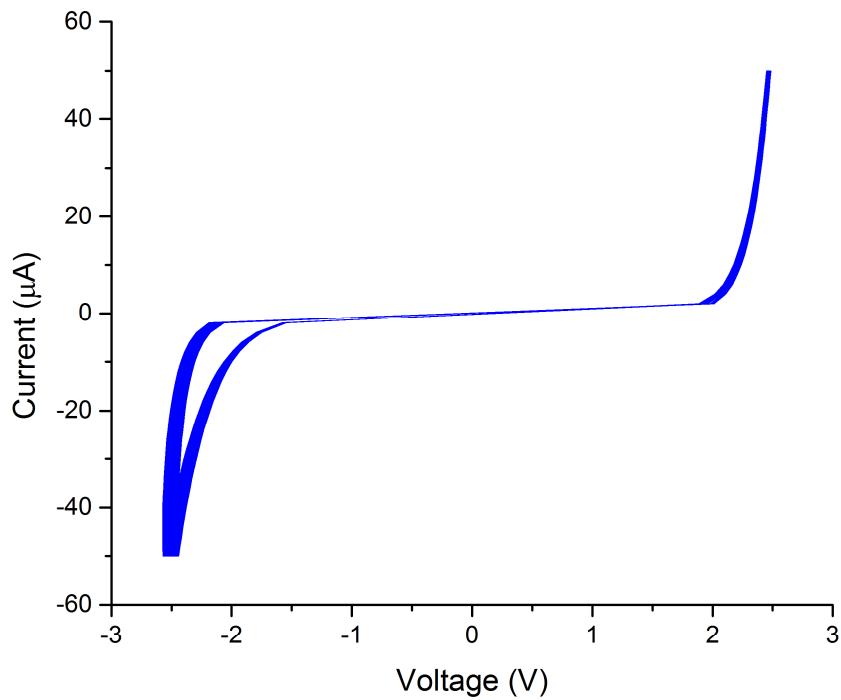
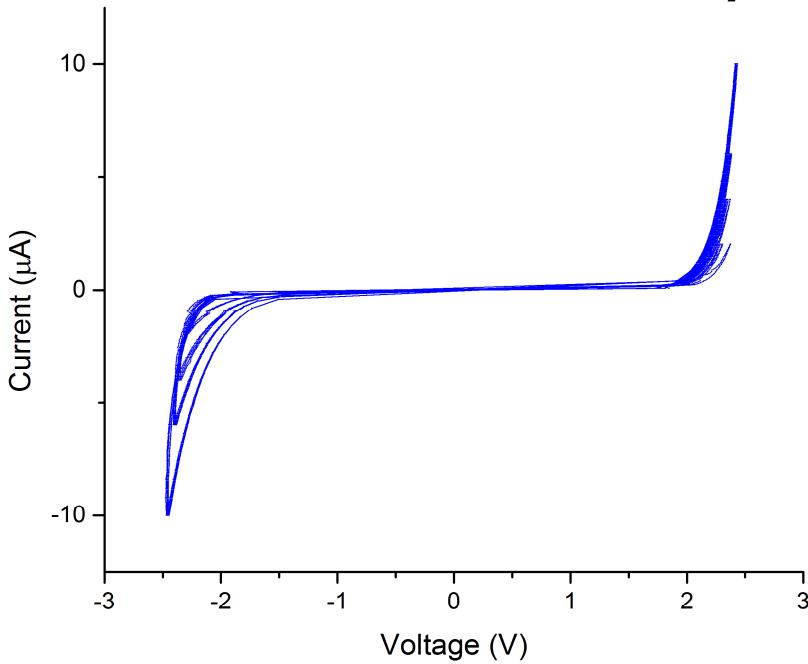
MicroFab Dot Caps

- Microfab Memristors
- Truly forming free
- Control On/Off ratio
- Consistency!
- Reproducibility?



More MicroFab Dot Caps

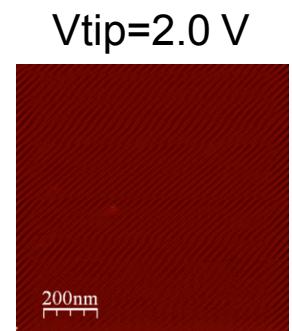
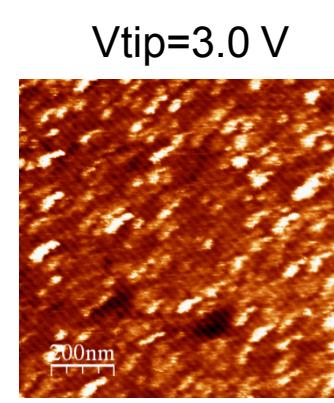
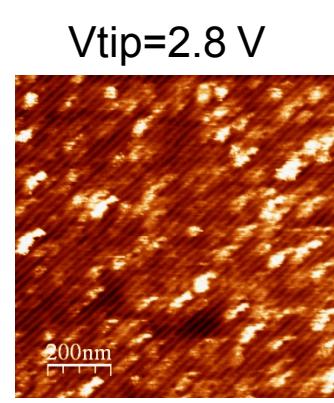
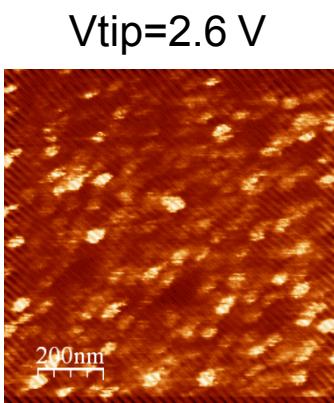
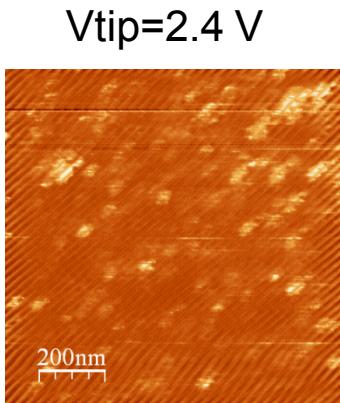
- Highly Nonlinear
- High Resistance
- Forming Free
- Good Consistency





Hot Spot Mapping

- Localized hot spots exist in the films suggesting the spire model is likely.



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20120806_swh-16-38_TaOx-CAFM_0009

20120806_swh-16-38_TaOx-CAFM_0010

20120806_swh-16-38_TaOx-CAFM_0011

20120806_swh-16-38_TaOx-CAFM_0012

Preamp Gain = 10^9 V/A

Same spot imaged with increasing tip voltage

Brighter colors indicate more conduction

